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Raman scattering studies of resistance-changing NiO films with and without IrO₂ buffer layers¹ S. YOON, E. CHO, Division of Nano Sciences and Department of Physics, Ewha Womans University, Seoul, Korea, H. CHEONG, Department of Physics, Sogang University, Seoul, Korea, S. SEO, Samsung Advanced Institute of Technology, Korea, B. SCHULZ, M. RUEBHAUSEN, Institute of Applied Physics, University of Hamburg, Hamburg, Germany — NiO films are known to exhibit resistive memory switching behavior and inserting thin IrO₂ layers between electrodes and the NiO film is claimed to minimize the dispersion of memory switching parameters, thus greatly improving the device properties. We present Raman scattering results of a NiO film, a NiO film with a 20 nm-thick IrO₂ layer, and a NiO film with a 50 nm-thick IrO₂ layer. We discuss the microscopic structural changes in the three different films and their relations to the switching behavior changes. We also discuss the role of IrO₂ buffer layers in the device structures.

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S. Yoon Ewha Womans University

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